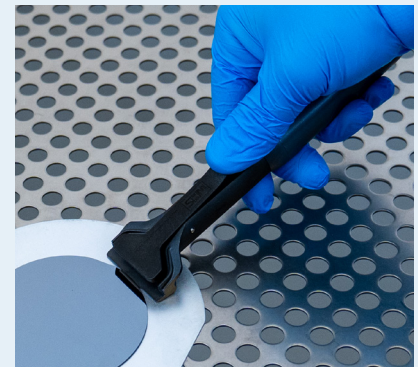
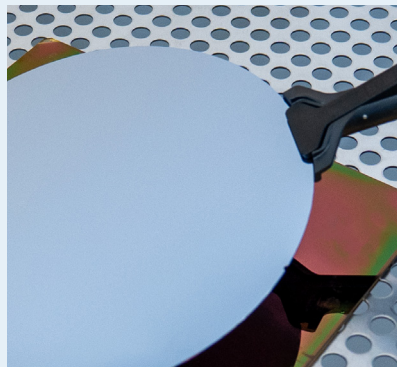
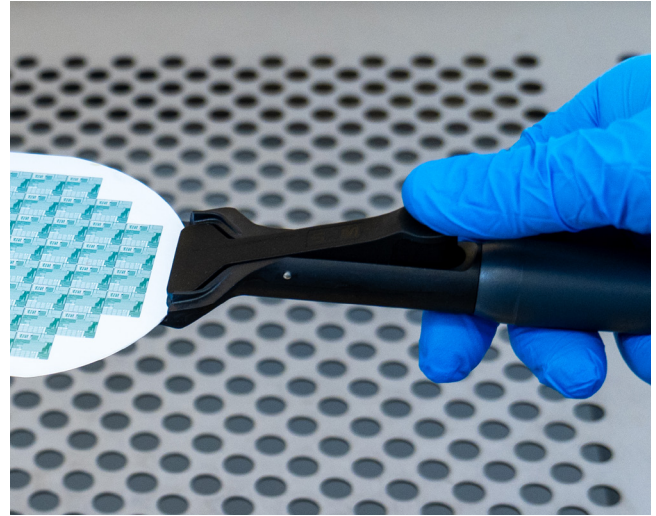


# MANUAL WAFER PICK WITH SPATULA KNIFE EDGE

The WHS-G2 series is an advanced manual wafer handling tool, designed specifically for applications requiring precise wafer manipulation on flat surfaces. A sister product to the WHS-G1, the WHS-G2 features a knife-edge spatula, ideal for lifting wafers from hotplates, platens, or vacuum chucks. This normally-closed, edge-only mechanical gripper accommodates wafers with thicknesses ranging from 120  $\mu\text{m}$  to 1000  $\mu\text{m}$ , ensuring secure handling in a variety of semiconductor processes.

The knife-edge spatula is compatible with surfaces up to 160°C, making the WHS-G2 an ideal solution for high-temperature wafer handling. The bottom gripper is constructed from ESD-safe PEEK for durability, antistatic protection, and chemical resistance. The top gripper side of the tool features a 3 mm perfluorocarbon



elastomer touchpad, which provides gentle, secure contact without risking scratches or contamination.

The ergonomic handle and easy-to-use trigger design enhance operator control and reduce fatigue, enabling safe handling of SEMI Standard round substrates, both silicon and compound wafers. In addition to standard wafer handling tasks such as manual transferring and sorting, the WHS-G2 is suited for specialty handling applications, including bonded and Taiko wafers, optical components, and MEMS devices.

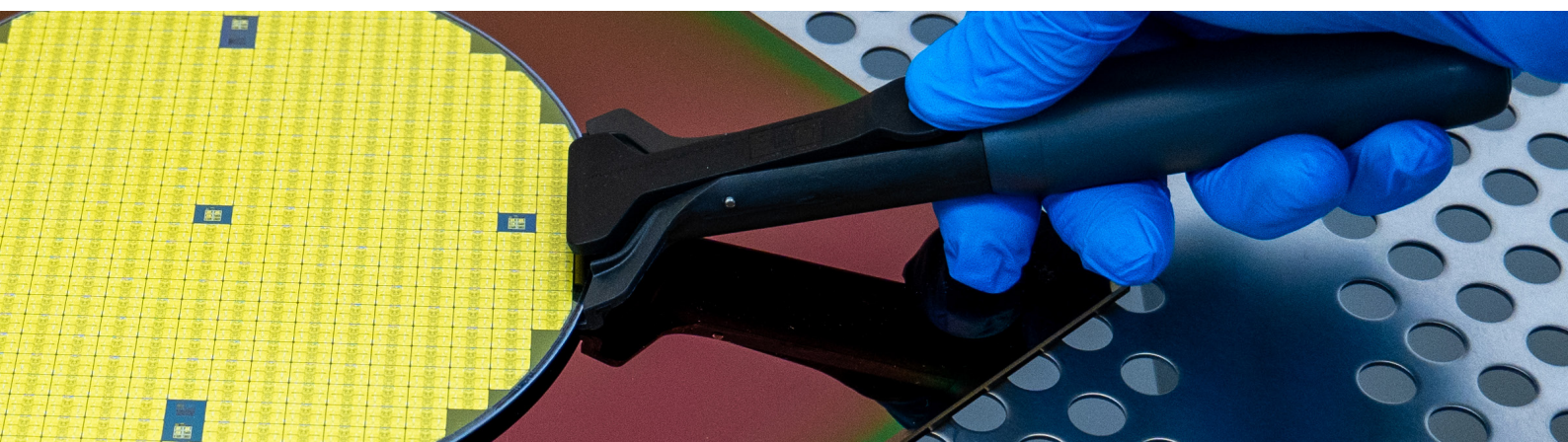
Offering a cost-effective alternative to vacuum wands and tweezers, the WHS-G2 ensures precise handling without scratching or leaving debris. Manufactured in an ISO9001 certified facility and with CE certification, the WHS-G2 meets international standards for performance and safety, making it an indispensable tool in cleanroom environments.

## FEATURES AND ADVANTAGES

- Knife-edge spatula for precise wafer lifting from hot surfaces
- Handles wafers on hotplates and platens up to 160°C
- ESD-safe PEEK construction for antistatic protection
- 3 mm perfluorocarbon touchpad for scratch-free contact
- Ergonomic design with easy trigger for secure handling

## MANUAL WAFER PICK WITH SPATULA KNIFE EDGE

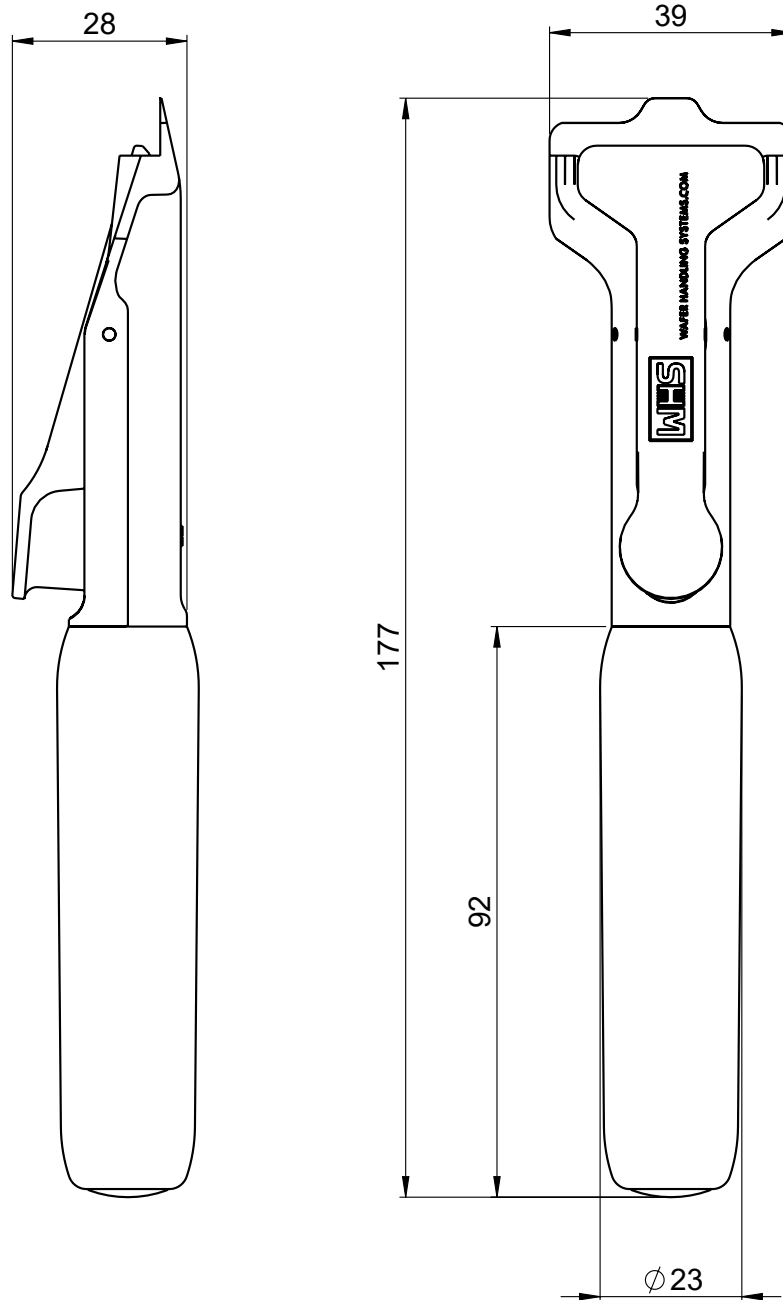
ITEM	SPECIFICATIONS
Wafer sizes	50-76, 100-125, 150, 200 mm
Material, bottom grip	Antistatic PEEK
Material, top grip	Perfluorocarbon elastomer
Grip hold	Normally closed
Cleanliness	ISO 4 (Class 10 FS209E)



### ORDERING INFORMATION

WHS-G2 -	23
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CODE	MODEL
23	Mechanical wafer pick, 50-76 mm wafer with spatula
45	Mechanical wafer pick, 100-125 mm wafer with spatula
6	Mechanical wafer pick, 150 mm wafer with spatula
8	Mechanical wafer pick, 200 mm wafer with spatula

**Materials:**

Handle: Antistatic Polycarbonate

Trigger: Polyamide

Body/Gripper: Antistatic PEEK

Wafer Touchstrip: Perfluoro Elastomer

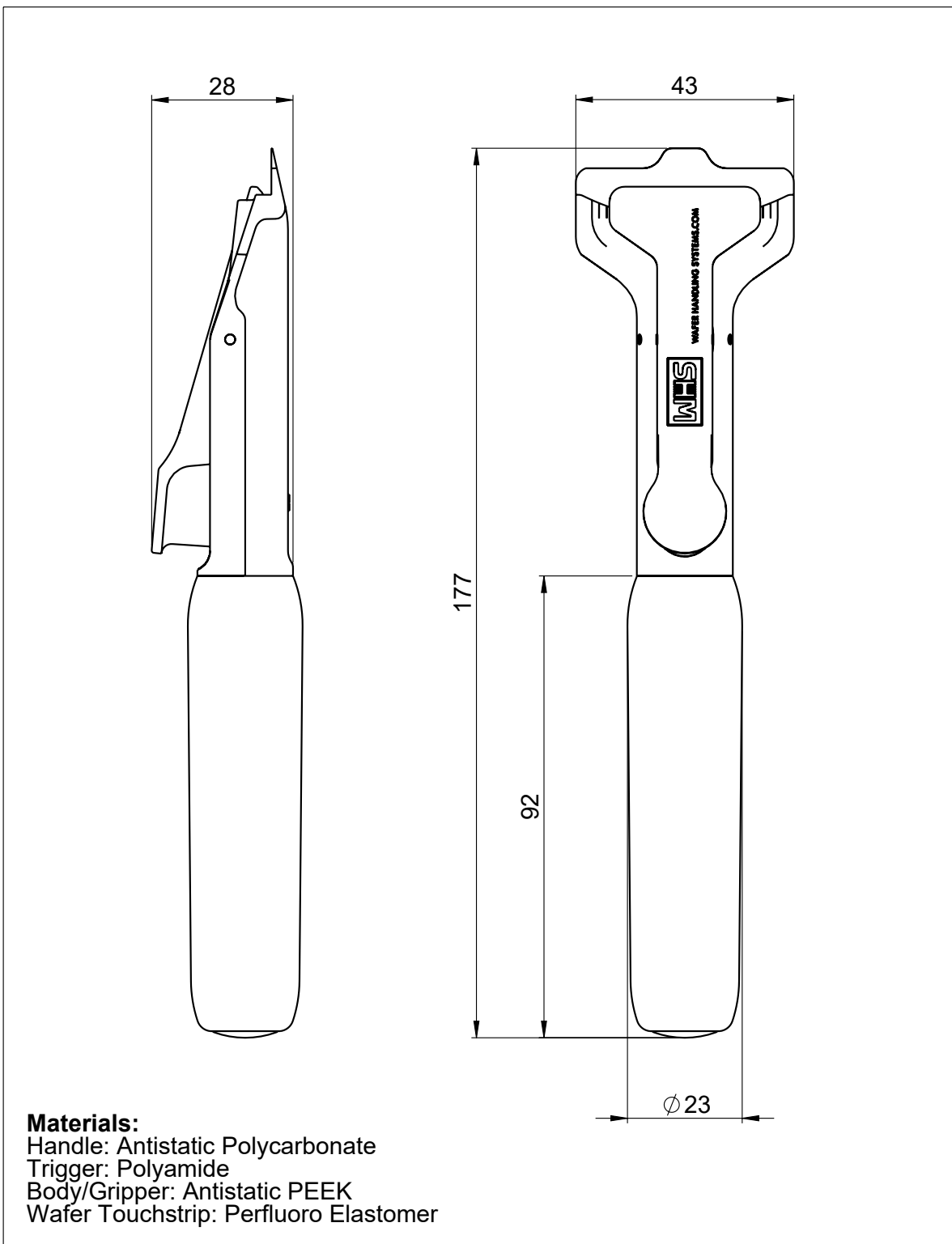


WAFER HANDLING SYSTEMS.COM

**WHS-G2-23**

Mechanical gripper assy, 50-76mm wafer with spatula

date: 01-10-2022 | scale: 1:1 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.



**Materials:**  
 Handle: Antistatic Polycarbonate  
 Trigger: Polyamide  
 Body/Gripper: Antistatic PEEK  
 Wafer Touchstrip: Perfluoro Elastomer

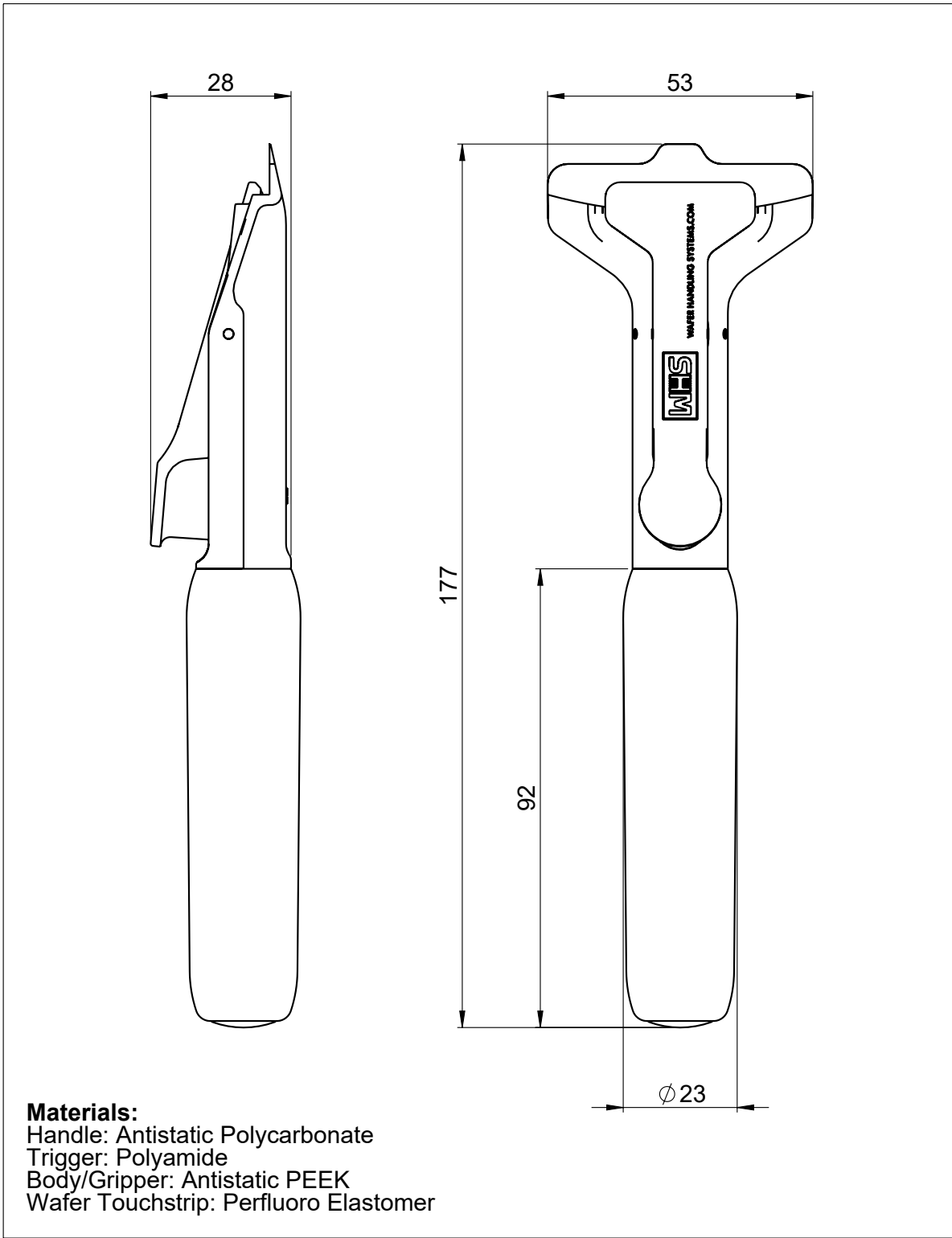


## WHS-G2-45

Mechanical gripper assy, 100-125mm wafer with spatula

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REV122024



**Materials:**  
 Handle: Antistatic Polycarbonate  
 Trigger: Polyamide  
 Body/Gripper: Antistatic PEEK  
 Wafer Touchstrip: Perfluoro Elastomer

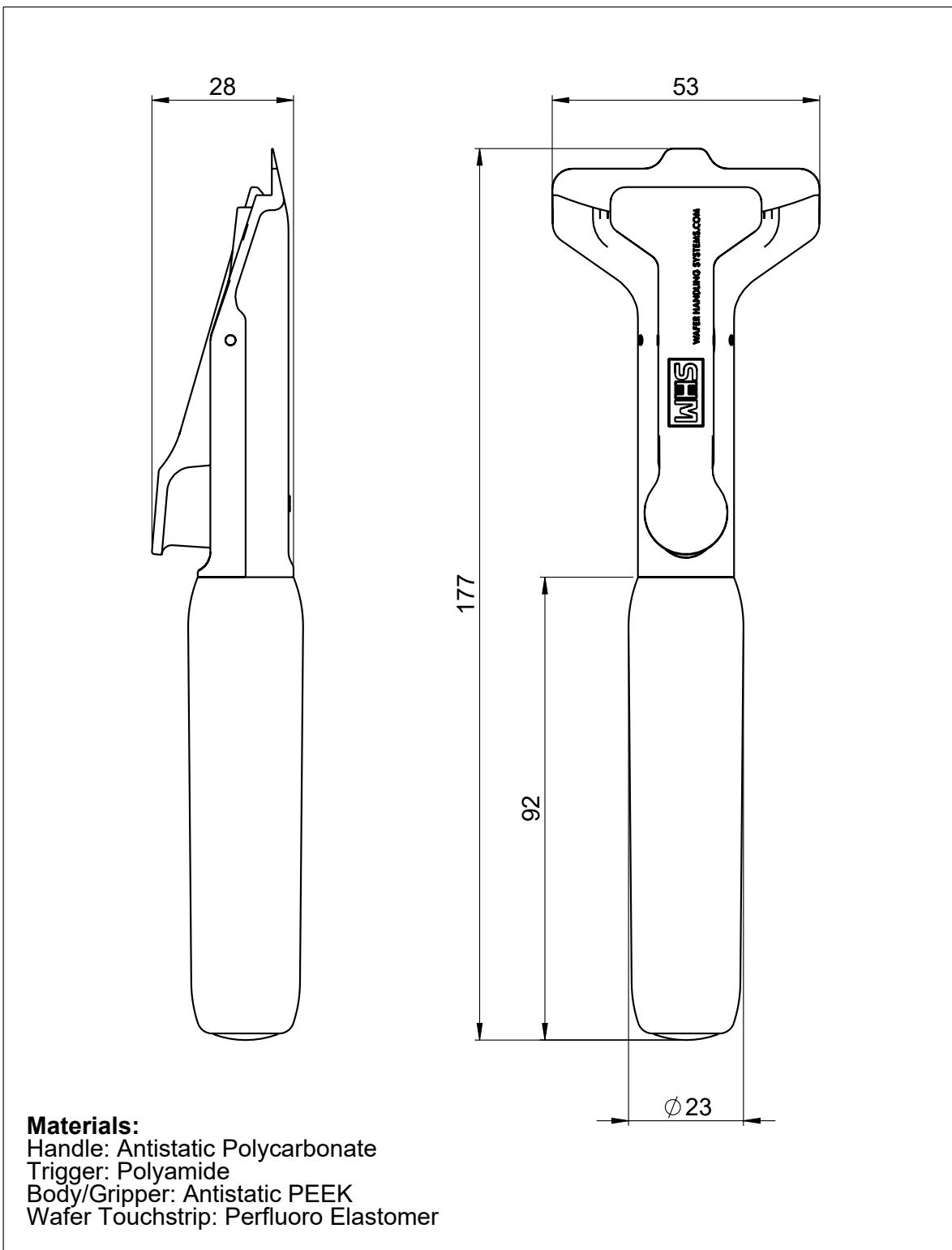


# WHS-G2-8

Mechanical gripper assy, 200mm wafer with spatula

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REV122024



**Materials:**  
 Handle: Antistatic Polycarbonate  
 Trigger: Polyamide  
 Body/Gripper: Antistatic PEEK  
 Wafer Touchstrip: Perfluoro Elastomer



## WHS-G2-6

Mechanical gripper assy, 150mm wafer with spatula

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